RF PLASMA DECONTAMINATOR

This easy to use tabletop model easily removes atmospheric hydrocarbons and carbon contamination from SEMs, FIBs, and other vacuum chambers. The Evactron® 25 De-Contaminator uses a remote RF plasma to produce gas-phase radicals that flow downstream through the chamber, eliminating contamination. Join over 1,200 users worldwide, and get the best possible performance and images from your instrument with regular Evactron® Cleaning. A simple button push enables the VentDetect™ Evactron Cleaning start process.

Features & Benefits

- VentDetect™ Technology
- Remove unwanted carbon contamination from your instrument
- Easy setup and operation
- Can be used on nearly all makes and models of electron microscopes
- Start cleaning by using chamber vent and evacuation controls
- Preset pressure, power and time settings from front panel or computer interface
- Just use air for oxygen radicals, or use other gases for alternative plasma processes
- Advanced plasma detection logic
- Cleaning and error logs record use history and aid troubleshooting
- KF 40 vacuum mounting flange, adapter flanges available
- Wide Pressure Range
- Free 5 year limited warranty
Specifications and Ordering Information

Power
RF Power: 5-20 Watts at 13.56 MHz

Utilities
90-250 VAC 50/60 Hz input

Physical
Electronic chassis: H, W, D: 5.5" x 9.375" x 9.75"
(14 x 24 x 25 cm). Shipping weight 16 lbs. (8 kg.)

Compliance
RoHS

Ordering Information:

Evactron® Model 25 Plasma Cleaner, Part # 233425-01

Additional PRS (Plasma Radical Sources) available

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